

Atty. Docket No. PIA31205/ANS/US  
Application No.: 10/764,905

Amendments to the Title

Please amend the Title as shown below:

METHODS FOR FORMING AN AIR GAP IN A SEMICONDUCTOR METAL  
LINE IN A SEMICONDUCTOR MANUFACTURING PROCESS

Atty. Docket No. PIA31205/ANS/US  
Application No.: 10/764,905

Amendments to the Specification

Please replace the Title at page 1, lines 1-3, with the following replacement:

METHODS FOR FORMING AN AIR GAP IN A SEMICONDUCTOR METAL  
LINE IN A SEMICONDUCTOR MANUFACTURING PROCESS